


INFORMATION DISCLOSURE CITATION <i>(Use several sheets if necessary)</i>				Docket Number (Optional) 11675.1 1.1		Application Number 09/392,034	
				Applicant(s) Gonzalez, et al.			
				Filing Date September 8, 1999		Group Art Unit 2812	
				U.S. PATENT DOCUMENTS			

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
/A.M./	1	3,791,882	Feb. 1974	Ogiue	438	417	
	2	4,409,609	Oct. 1983	Fukuda	257	520	
	3	4,717,682	Jan. 1988	Taka et al.	438	361	
	4	4,819,052	Apr. 1989	Hutter	257	378	
	5	4,965,221	Oct. 1990	Dennison et al.	437	70	
	6	5,045,904	Sep. 1991	Kobayashi et al.	257	539	
	7	5,221,857	Jun. 1993	Kano	257	539	
	8	5,229,316	Jul. 1993	Lee et al.	438	424	
	9	5,387,534	Feb. 1995	Prall	438	287	
	10	5,433,794	Jul. 1995	Fazan et al.	148	33	
	11	5,541,440	Jul. 1996	Kozai et al.	257	513	

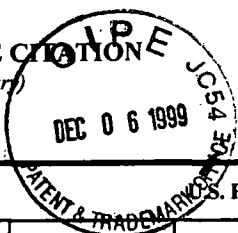
FOREIGN PATENT DOCUMENTS								
	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO

OTHER DOCUMENTS <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>		
/A.M./	12	S. Wolf, Silicon Processing for the VLSI Era, Vol. 2; Process Integration, Lattice Press, pp. 54-56, 1990.
/A.M./	13	Stanley Wolf, Silicon Processing for the VLSI Era, Vol. 2: Process Integration, Lattice Press, p. 331, 1990.

EXAMINER /Anh Mai/	DATE CONSIDERED 08/09/2007
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)



Docket Number (Optional) 11675.11.1		Application Number 09/392,034
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U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
/A.M./	14	5,780,325	Jul. 1998	Lee	438	149	

FOREIGN PATENT DOCUMENTS

/A.M./	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

/A.M./	15	T. Ishijima, et al., "A Deep Sub-Micron Isolation Technology With T-Shaped Oxide (TSO) Structure," IEEE Publication No. Ch2865-4/90/0000-0257 (1990), pp. 257-260.

EXAMINER /Anh Mai/	DATE CONSIDERED 08/09/2007
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